

WG-6 summary

WG6: TE/MPE/EM Workshop upgrade

- Last year, agreement was reached with CERN management to purchase the subset of machines necessary to carry out R&D on large size GEM (2m x 0.5 m) & Micromegas (2m x 1m) and the associated large size read-out boards in the current CERN TE/MPE/ME facility.

GEM	market survey	call for tender	order	received	ready
– 1 continuous polyimide etcher	x	x	x	x	06/2011
– 1 Cu electroetch line	x	x	x		06/2011
Micromegas					
– 1 large laminator	x	x	x		06/2011
– 1 large Cu etcher	x				09/2011
– 1 large UV exposure unit	x	x	x	x	06/2011
– 1 large resist developer	x				09/2011
– 1 large resist stripper	x				09/2011
– 1 large oven	x	x	x	x	06/2011
– 1 large dryer	x	x	x	x	06/2011

- **CERN investment:**

- Equipments for large size GEM manufacturing (2m x 0.5m goal)
- Equipments for large size Micromegas manufacturing (2m x 1m goal)
- Participation of 4 technicians (15% of their time)

- **Participation from AIDA:**

- Finance a technician during 2 years to:
 - Set up the equipments
 - Produce some large prototypes for: (non exhaustive list)

Transfer to industry

- **Micromegas:**

- Cirea → handled by Saclay → one std Bulk produced successfully
- Eltos ? Do we start something?
- US → handled by V.Polychronakos/BNL → large PCB produced and BULK?
- Other companies ?
- Resistive coatings?

- **GEMs:**

- New-Flex → Handled by CERN/ Corea . 100 x 100 GEM are being produced
- Micrometal → problem of width → stop?
- India → few information. Waiting for their visit at CERN

- Techetch/USA
- Scienergy/Japan